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## \*\* CONTINUING DATA \*\*\*\*\*

This application is a CIP of 10/279,961 10/23/2002 PAT 6,802,944 *jm*

## \*\* FOREIGN APPLICATIONS \*\*\*\*\*

*none*

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 12/03/2003

Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	STATE OR COUNTRY CA	SHEETS DRAWING 12	TOTAL CLAIMS 28	INDEPENDENT CLAIMS 3
35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	Verified and Acknowledged	Examiner's Signature <i>m</i>	Initials	

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## TITLE

Reactive ion etching for semiconductor device feature topography modification

FILING FEE	FEES: Authority has been given in Paper	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of
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